

Special Issue

RF Devices: Technology and Progress

Message from the Guest Editor

RF MEMS is a type of MEMS device that processes radio frequency signals. RF MEMS can utilize MEMS technology to manufacture on-chip transmission lines, RF cavities, three-dimensional inductors, couplers, varactors, switches, filters, phase shifters and antennas. Compared with traditional RF devices, RF MEMS devices have many advantages, including their small size, insensitivity to acceleration, low DC power consumption, and ability to be fabricated on low-cost silicon or glass substrates. In addition, RF MEMS devices can be integrated with traditional silicon-based and gallium arsenide-based circuits, enabling miniaturization of RF processing systems. These advantages have led to significant applications in fields such as mobile communications, satellites, radars, etc. Accordingly, this Special Issue seeks to showcase research papers, short communications, and review articles that focus on novel technology and progress in RF MEMS and its use for various RF systems.

Guest Editor

Dr. Lifeng Wang

Key Laboratory of MEMS of the Ministry of Education, School of Electronic Science & Engineering, Southeast University, Nanjing 210096, China

Deadline for manuscript submissions

closed (28 February 2026)



Micromachines

an Open Access Journal
by MDPI

Impact Factor 3.0
CiteScore 6.0
Indexed in PubMed



mdpi.com/si/217667

Micromachines
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
micromachines@mdpi.com

[mdpi.com/journal/
micromachines](https://mdpi.com/journal/micromachines)





Micromachines

an Open Access Journal
by MDPI

Impact Factor 3.0
CiteScore 6.0
Indexed in PubMed



[mdpi.com/journal/
micromachines](https://mdpi.com/journal/micromachines)



About the Journal

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Editor-in-Chief

Prof. Dr. Nam-Trung Nguyen

Queensland Quantum and Advanced Technologies Research Institute,
Griffith University, West Creek Road, Nathan, QLD 4111, Australia

Author Benefits

High Visibility:

indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank:

JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

Rapid Publication:

manuscripts are peer-reviewed and a first decision is provided to authors approximately 16.8 days after submission; acceptance to publication is undertaken in 1.9 days (median values for papers published in this journal in the second half of 2025).